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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In application of:

Walter SCHWARZENBACH et al.

Confirmation No.: 7150

Application No.: 10/716,612

Group Art Unit: 1742

Filing Date: November 20, 2003

Examiner:

For: ANNEALING PROCESS AND DEVICE
OF SEMICONDUCTOR WAFER

Attorney Docket No.: 4717-7700

SECOND INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to applicants' duty of disclosure under 37 C.F.R. § 1.56, enclosed is a copy of one (1) reference for the Examiner's review and consideration. The reference is listed on the enclosed Form PTO-1449. Also enclosed is a copy of the International Search Report from the corresponding foreign application on which the reference was cited. It is respectfully requested that the reference be made of record in this application by the Examiner's completion and return of the Form PTO-1449.

This Information Disclosure Statement is filed under 37 C.F.R. § 1.97(b) before the latter of three months after the U.S. patent application filing date or the first Office Action on the merits. Accordingly, no fee or certification is required. Should any fees be required, however, please charge such fees to Winston & Strawn LLP Deposit Account No. 50-1814.

Respectfully submitted,

9/2/04

Date

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